

# OPTICAL NEAR-FIELD NANO-POLISHING OF THE QUARTZ SUBSTRATE SURFACE

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## Abstract

The results of the study of optical near-field nano-polishing of the quartz substrate surface are presented. The results obtained demonstrate a sharp decrease in the level of roughness of the quartz substrate surface, which confirms the efficiency of this method. The proposed technique is highly effective in surface nanotechnology.

## Type of Book of Abstracts

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